Docket No. 206342US2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Toshifumi NAGAIWA, et al.

GAU:

SERIAL NO: New Application

EXAMINER:

FILED:

Herewith

FOR:

WORKTABLE DEVICE AND PLASMA PROCESSING APPARATUS FOR SEMICONDUCTOR PROCESS

REQUEST FOR PRIORITY

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

COUNTRY

- ☐ Full benefit of the filing date of U.S. Application Serial Number, filed, is claimed pursuant to the provisions of 35 U.S.C. §120.
- ☐ Full benefit of the filing date of U.S. Provisional Application Serial Number, filed, is claimed pursuant to the provisions of 35 U.S.C. §119(e).
- Applicants claim any right to priority from any earlier filed applications to which they may be entitled pursuant to the provisions of 35 U.S.C. §119, as noted below.

In the matter of the above-identified application for patent, notice is hereby given that the applicants claim as priority:

APPLICATION NUMBER

JAPA	N	2000-123540	April 25, 2000
JAPA	N	2000-323208	October 23, 2000
Certified copies of the corresponding Convention Application(s)			
	are submitted herewith		
	will be submitted prior to payment of the Final Fee		
	were filed in prior application Serial No. filed		
	were submitted to the International Bureau in PCT Application Number. Receipt of the certified copies by the International Bureau in a timely manner under PCT Rule 17.1(a) has been acknowledged as evidenced by the attached PCT/IB/304.		
	(A) Application Serial No.(s)	were filed in prior application Serial No. fil	led; and
	(B) Application Serial No.(s)		
	□ are submitted herewith		
	☐ will be submitted prior	to payment of the Final Fee	

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

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